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## Hybrid Schottky and Heterojunction Vertical $\beta$ -Ga<sub>2</sub>O<sub>3</sub> Rectifiers

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### ABSTRACT

Junction Barrier Schottky design Ga<sub>2</sub>O<sub>3</sub> rectifiers allow for a combination of low turn-on  
voltage and high breakdown voltage. Ni/Au/Ga<sub>2</sub>O<sub>3</sub> Schottky rectifiers and NiO/Ga<sub>2</sub>O<sub>3</sub>  
heterojunction rectifiers were fabricated on the same wafer and the percentage of the relative areas  
and diameters of each were varied from pure Schottky devices to pure heterojunction devices. The  
on-voltage increased from 0.6 V for Schottky rectifiers to 2.4 V for heterojunction rectifiers, with  
a monotonic decrease in forward current at fixed bias of 5V from 375 nA.cm<sup>-2</sup> to 175 nA.cm<sup>-2</sup>.  
Conversely, the breakdown voltage increased monotonically as the proportion of heterojunction  
area increased, from 1.2 kV for Schottky rectifiers to 6.2 kV for pure heterojunction devices.  
Breakdown mostly was initiated at the edge of the anode contact but could also occur at the  
transition region from the Schottky contact to NiO edge termination. The Baliga figure of merit

1 increased with both the relative percentage of area and diameter of the heterojunction contact from  
2 0.2 GW.cm<sup>-2</sup> to 3GW.cm<sup>-2</sup>, while the energy loss during switching also increased from 2 to 3.9  
3 W.cm<sup>-2</sup>. These trends illustrate the trade-offs of Schottky versus pn junctions for the operation of  
4 Ga<sub>2</sub>O<sub>3</sub> rectifiers.

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## 1 Introduction

2        There is significant recent interest in development of  $\text{Ga}_2\text{O}_3$  based rectifiers and transistors  
3 for advanced power electronic devices and RF amplifiers <sup>(1-7)</sup>. Their elevated critical electric field,  
4 coupled with reasonable transport characteristics and high permittivity, facilitates high-voltage  
5 operation within compact dimensions <sup>(8-13)</sup>. This characteristic mitigates parasitic capacitances and  
6 produces high switching efficiencies in applications such as power conversion in electric vehicles  
7 and smart grids <sup>(1-3, 12, 13)</sup>. Additionally, it enables the attainment of the requisite power densities  
8 and power added efficiencies in future 5G/6G wireless communications and radar systems <sup>(1-3)</sup>.  
9 There is also growing interest in their utilization in radiation-hardened applications, notably for  
10 space-borne systems <sup>(14)</sup>.

11        Despite significant advancements in the bulk and epitaxial growth of the  $\beta$ -polytype of  $\text{Ga}_2\text{O}_3$ ,  
12 devices fabricated from this material have yet to achieve their maximum theoretical performance,  
13 particularly at high voltages and frequencies <sup>(2,4)</sup>. Achieving this entails gaining a deeper  
14 understanding of breakdown and charge transport mechanisms, electron-hole recombination  
15 processes, and interactions with charged defects under specific operational conditions <sup>(15-18)</sup>. This  
16 necessitates comprehensive experimental studies as well as modeling and simulation support.

17        A significant advance in breakdown voltages for  $\text{Ga}_2\text{O}_3$  based rectifiers has come from the  
18 development of  $\text{NiO}/\text{Ga}_2\text{O}_3$  pn heterojunctions <sup>(19-27)</sup>. Breakdown voltages up to 13.5 kV were  
19 recently demonstrated in small diameter (100  $\mu\text{m}$ ) vertical  $\text{NiO}/\text{Ga}_2\text{O}_3$  rectifiers and 7.2kV in large  
20 diameter (1 mm) devices <sup>(26)</sup>. These are both more than the theoretical 1D limit of performance of  
21 comparable GaN and SiC rectifiers, although those technologies are far more mature in terms of  
22 thermal management, defect control, reliability, surge robustness and packaging <sup>(1-4)</sup>. A promising  
23 approach is the Junction Barrier Schottky (JBS) diode, which integrates the beneficial

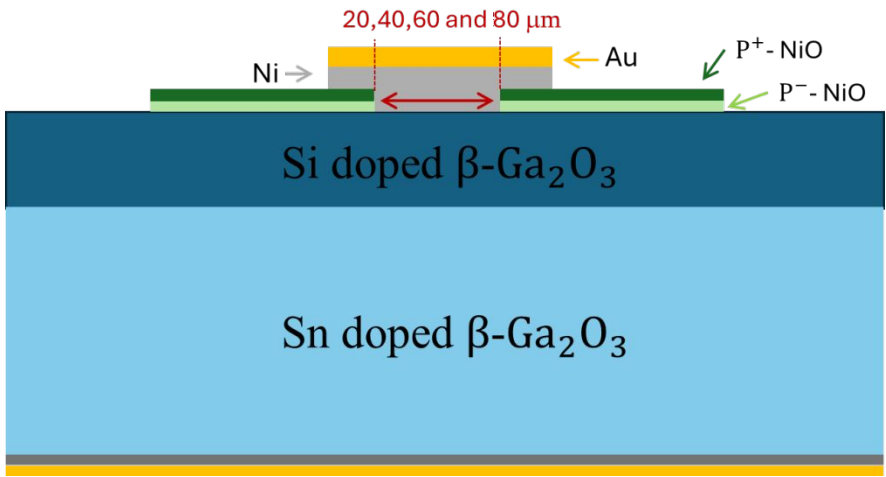
characteristics of Schottky Barrier Diodes (SBDs) and PiN diodes<sup>(1,4,8,12, 25)</sup>. The JBS diode features low conduction losses similar to SBDs in the on-state, while in the off-state, it exhibits improved leakage current and breakdown voltage akin to PiN diodes. This is achieved through a structure where a single anode forms a Schottky contact with the n-type drift layer and a connection with the  $p^+$  region, promoting depletion into the drift region under reverse bias. This structural configuration involves embedding  $p^+$  regions of NiO beneath the anode. Our structure deviates from traditional JBS structures by having the NiO deposited on the surface rather than embedded. During forward bias operation, the JBS diode behaves similarly to an SBD, where the Schottky portion conducts the current, though the specific on-resistance might increase due to reduced conduction area near the junction<sup>(1,4,8,12, 25)</sup>. Forward conduction is influenced by the geometry or cell pitch, with increased Schottky area enhancing current flow. In reverse bias, the electric field profile initially resembles that of an SBD, but upon reaching a certain reverse bias, the Schottky portion becomes fully depleted, resembling the field profile of a PiN diode and enhancing blocking capabilities.

There are still many more systematic studies of  $\text{Ga}_2\text{O}_3$  rectifier design needed to advance this technology. In this work, we study the effect of systematically varying the relative area of Schottky and heterojunction rectifiers fabricated on the same wafer to understand the effect on forward turn-on voltage, reverse breakdown voltage, power figure of merit and switching losses.

## Experimental

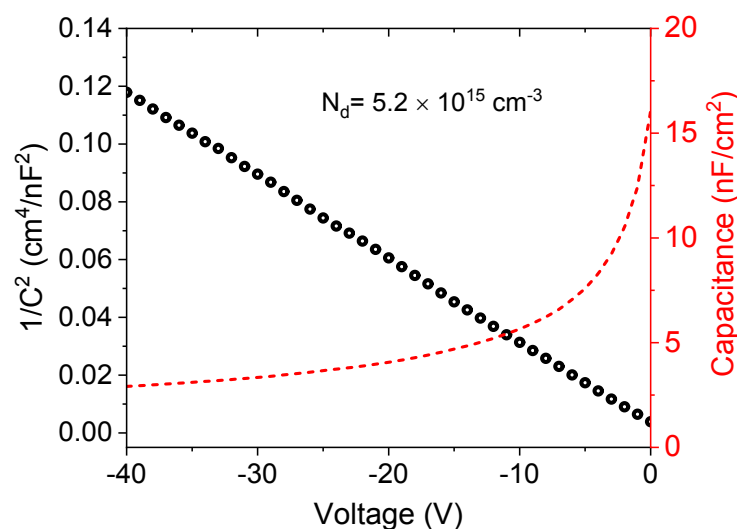
The rectifiers were fabricated on thick ( $\sim 10\ \mu\text{m}$ ) lightly doped epitaxial layers grown by Halide Vapor Phase Epitaxy on heavily doped ( $n\sim 8\times 10^{18}\ \text{cm}^{-3}$ ) bulk substrates with (001) orientation grown by the Edge- Defined Film-Fed technique. Ohmic contacts were formed on the backside of the wafers by deposition of e-beam evaporated Ti/Au. This was subsequently annealed

at 550 °C for 3 min. Both Schottky barrier diodes (SBD) pure heterojunction diodes (HJD) and JBS diodes were fabricated on the same wafer, with the schematic structure shown in **Figure 1**. A bilayer of Ni/Au was used for the Schottky contact and to make contact to the p<sup>+</sup>NiO deposited by sputtering. Deposition conditions for the bilayer NiO have been reported previously <sup>(28)</sup>. In brief, this is done at low sputtering powers and the doping concentrations for the respective layers were 2.6 x 10<sup>18</sup> cm<sup>-3</sup> for the upper layer with a thickness of 10 nm, and 10<sup>18</sup> cm<sup>-3</sup> for the 10 nm lower layer, as controlled through the O<sub>2</sub> ratio during sputtering <sup>(28)</sup>. Thus, the hybrid JBS structure consists of an area with Schottky behavior and a different area where a heterojunction rectifier is formed. The ratio of the two areas was varied between the two extremes (100% Schottky or 100% heterojunction) by varying the diameter of the opening where the Schottky contact was made. This diameter was varied from 20-80 μm, while the diameter of the Ni/Au contact was held constant at 100 μm. All the devices were fabricated on a 1 cm x 1 cm sample. The opening diameter of NiO varies. The percentage of the Schottky contact area was varied from 4-64%. Measurements from five devices of each structure were performed. The NiO/Ni/Au behaves as an Ohmic contact.



**Figure 1.** Schematic of the hybrid devices. The diameter of the Ni/Au Schottky contact on the Ga<sub>2</sub>O<sub>3</sub> was increased from 20-80  $\mu\text{m}$ , while holding the total diameter of the contact constant. This effectively varies the percentage of the device that has Schottky behavior relative to that which has NiO/Ga<sub>2</sub>O<sub>3</sub> heterojunction behavior.

The carrier concentrations within the drift regions of the devices were quantified utilizing 1 MHz capacitance-voltage (C-V) measurements, with subsequent plotting of  $1/C^2$ -V data. **Figure 2** depicts the C-V and  $1/C^2$ -V plots corresponding to 10  $\mu\text{m}$  thick drift layers, showing the carrier concentrations were  $5.2 \times 10^{15} \text{ cm}^{-3}$  in the drift region.



**Figure 2.** C-V and  $C^{-2}$ -V characteristics to extract doping in drift layer.

Current-voltage (I-V) characteristics were assessed under Fluorinert atmospheres at a temperature of 25°C, employing a Tektronix 371-B curve tracer in tandem with a Glassman high-voltage power supply. Low voltage forward and reverse current characteristics were analyzed using an Agilent 4156C parameter analyzer. The determination of the reverse breakdown voltage adhered to the conventional criterion, where reverse current density reached 0.1 A/cm<sup>2</sup>. A mega-Ohm resistor was incorporated into the setup, and the resultant voltage drop across it was deducted.

Furthermore, prior to each breakdown test, contact integrity was ensured by conducting a forward sweep up to 5V, followed by a reverse sweep up to -100V, and confirming the I-V characteristics. On-resistance was derived from the voltage-current ( $dV/dI$ ) derivative extracted from the I-V characteristics. Corrections were applied to compensate for the resistance contributed by external circuit components, encompassing cables, chuck, and probe, collectively amounting to 10  $\Omega$ , determined through I-V measurements while the cables, chuck, and probe were interconnected.

The dependence of forward current on perimeter to area ratio gives an indication of the relative contributions of surface and bulk current mechanisms <sup>(29)</sup>. We measured a range of parameters as a function of both the percentage area or diameter of the Schottky contact relative to the total anode contact area, including on-voltage ( $V_{on}$ ), breakdown voltage ( $V_{br}$ ) <sup>(30)</sup>, Baliga's figure-of-merit ( $V_B^2/R_{ON}$ ) and energy switching loss, defined as  $\text{Energy loss} = D \cdot P_{on} + (1-D) \cdot P_{OFF} = D \cdot V_F$  (at 100A/cm<sup>2</sup>)  $\cdot$  100 A/cm<sup>2</sup> + (1-D)  $\cdot$  100V  $\cdot$  I(at-100V), where D is the duty cycle (we used 1%).

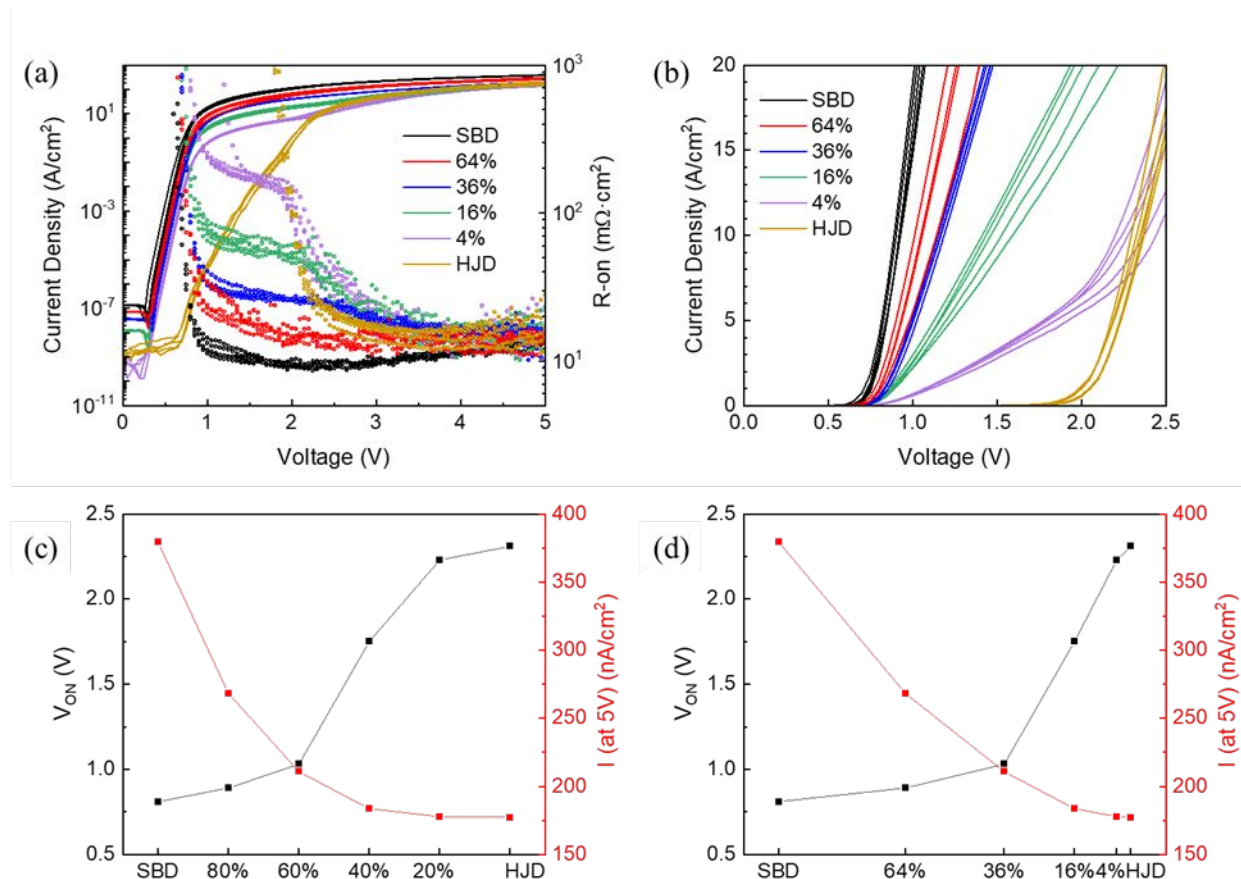
In addition, SILVACO TCAD simulations were performed to extract electric field and electron current density profiles <sup>(16)</sup>. This incorporates the necessary stress-dependent mobility and bandgap models, a high field saturation model, a trap-assisted Shockley-Read-Hall recombination model, a thermionic current model, a band gap narrowing model, and drift-diffusion and energy balance transport equations.

## Results and Discussion

**Figure 3 (a)** shows the forward J-V characteristics and related  $R_{on}$  values for the range of hybrid devices examined. Five devices of each type were measured. The pure Schottky diodes have the highest forward current and lowest  $R_{on}$  values ( $\sim 10 \text{ m}\Omega \cdot \text{cm}^2$ ) due to the lower effective barrier height compared to the heterojunction devices. The on-voltages could be derived from the slope of the linear J-A characteristics, shown in **Figure 3(b)**. These span from 0.75 V for Schottky



rectifiers to 2.3 to 2.4 V for pure heterojunction rectifiers. **Figure 3 (c)** shows the area dependence of  $V_{on}$  and forward current density at a fixed forward bias voltage of 5 V of the hybrid devices as a function of the Schottky contact area relative to the total area. The same data is shown in **Figure 3 (d)** as a function of the percentage of Schottky contact diameter relative to the total diameter of the hybrid devices. There is not a linear relationship of forward current in either case and this non-linear behavior can be explained by the effect of heterojunction thermionic emission of electrons from  $Ga_2O_3$  to NiO as shows in simulation figures in addition to the recombination current. Since current is not directly proportional to either area or perimeter, both bulk and surface current contributions are present.

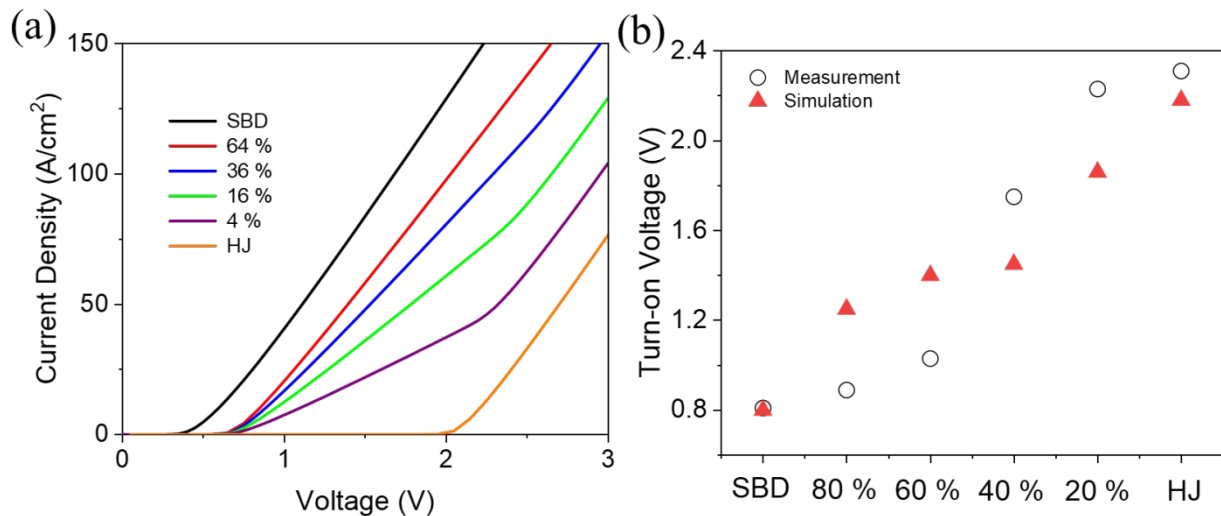


**Figure 3.** Forward current density plotted on a logarithmic scale (a) and a linear scale (b) as a function of bias for devices. (c) and (d) On-voltage and forward current at 5V bias for hybrid devices with varying percentages of the area and diameter of the Schottky contact respectively.

The nonlinear relationship between the on-voltage as a function of the Schottky contact area relative to the total area (**Figure 3 (c)**) or to the percentage of Schottky contact diameter relative to the total diameter (**Figure 3 (d)**) and forward current can be explained by the dominance of a new transport mechanism as the Schottky contact area decreases. The expected transport mechanism involves the transfer of electrons from  $\beta\text{-Ga}_2\text{O}_3$  to NiO and then to the Ni contact as we will confirm using Silvaco TCAD. Due to the ultrathin NiO layers, different mechanisms are anticipated, with thermionic emission and tunneling being the most probable <sup>(16, 20, 25)</sup>. In addition, surface recombination in Ni/ $\beta\text{-Ga}_2\text{O}_3$ , with a lesser effect in NiO/ $\beta\text{-Ga}_2\text{O}_3$ , may significantly impact the linear behavior of the forward current at different Schottky contact areas due to the influence of electron traps in the  $\beta\text{-Ga}_2\text{O}_3$  <sup>(31-35)</sup>.

There is, as yet no direct measurement of the surface recombination velocity of  $\beta\text{-Ga}_2\text{O}_3$  although numerous studies have shown the surface is easily disrupted by dry etching steps or thermal degradation <sup>(31-35)</sup>. Bulk leakage contributions may originate from stacking faults, polycrystalline inclusions and dislocations present in the drift region <sup>(15, 32- 39)</sup>. Furthermore, as shown in **Figure 3 (b)**, we observed transitions in the slopes of the linear regions at high forward voltages in the 16% and 4% hybrid junction diodes. To understand the underlying reasons for this behavior, we utilized SILVACO TCAD simulations. First, as shown in Figure 4(a) the simulated current density for all devices, we noticed the formation of the transition slopes for the cases 16 % and 4 % hybrid junction diodes which highly agree with the measured behavior. However there

are minor deviation between simulations and measurements as shown in **Figure 4 (b)**. This small deviation explained by the effect of interfacial states in NiO/ $\beta$ -Ga<sub>2</sub>O<sub>3</sub> interface.

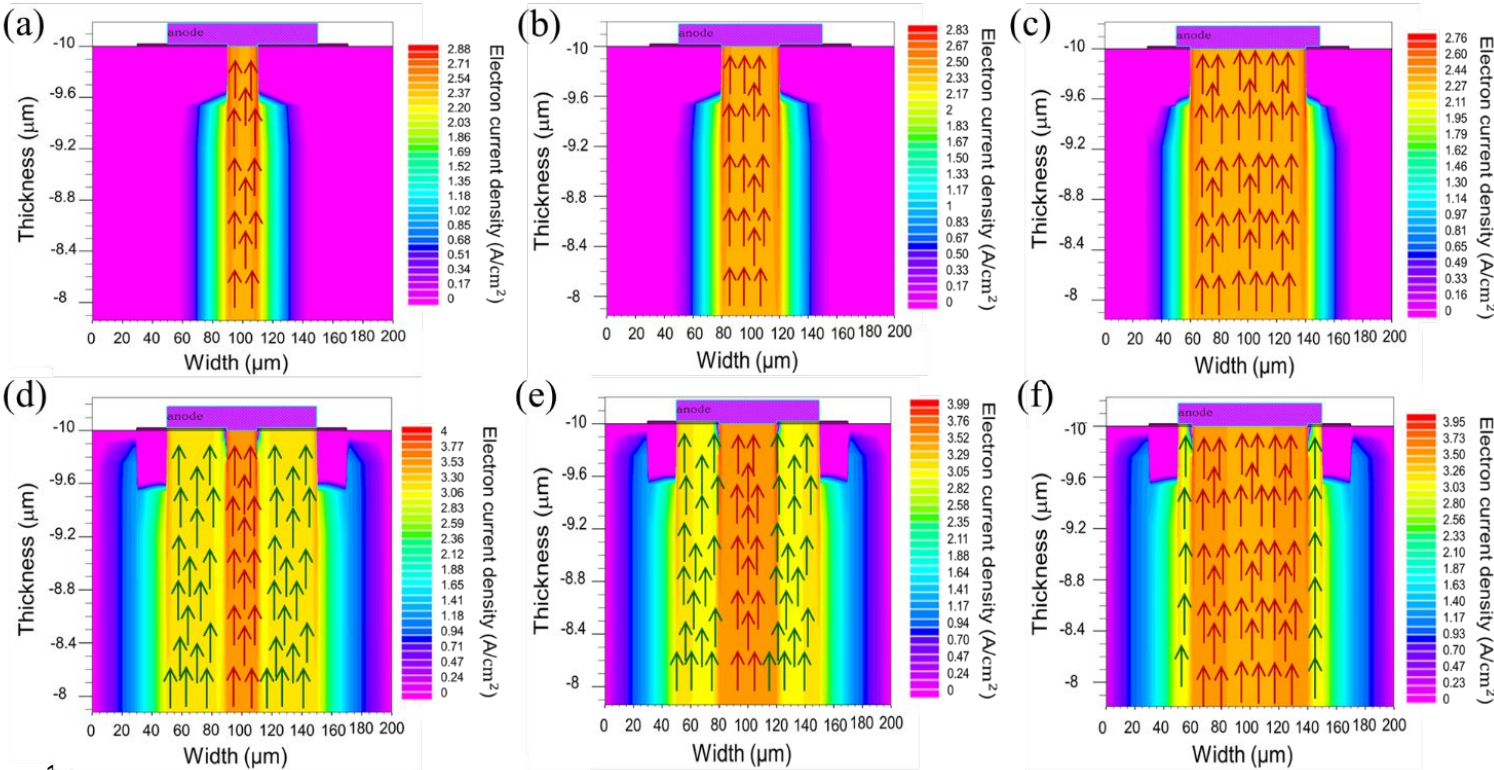


**Figure 4.** (a) Simulated forward current density plotted on a linear scale and (b) Simulated on-voltage for hybrid devices with varying percentages of the area and diameter of the Schottky contact and compared with measurement.

Now, to deeply understand the reason of the observed transitions in the slopes of the linear regions at high forward voltages in the 16% and 4% hybrid junction diodes, we compared the electron current density under +1 V and +4 V for both 16% and 4% hybrid junction diodes with that of the 64% hybrid junction diode.

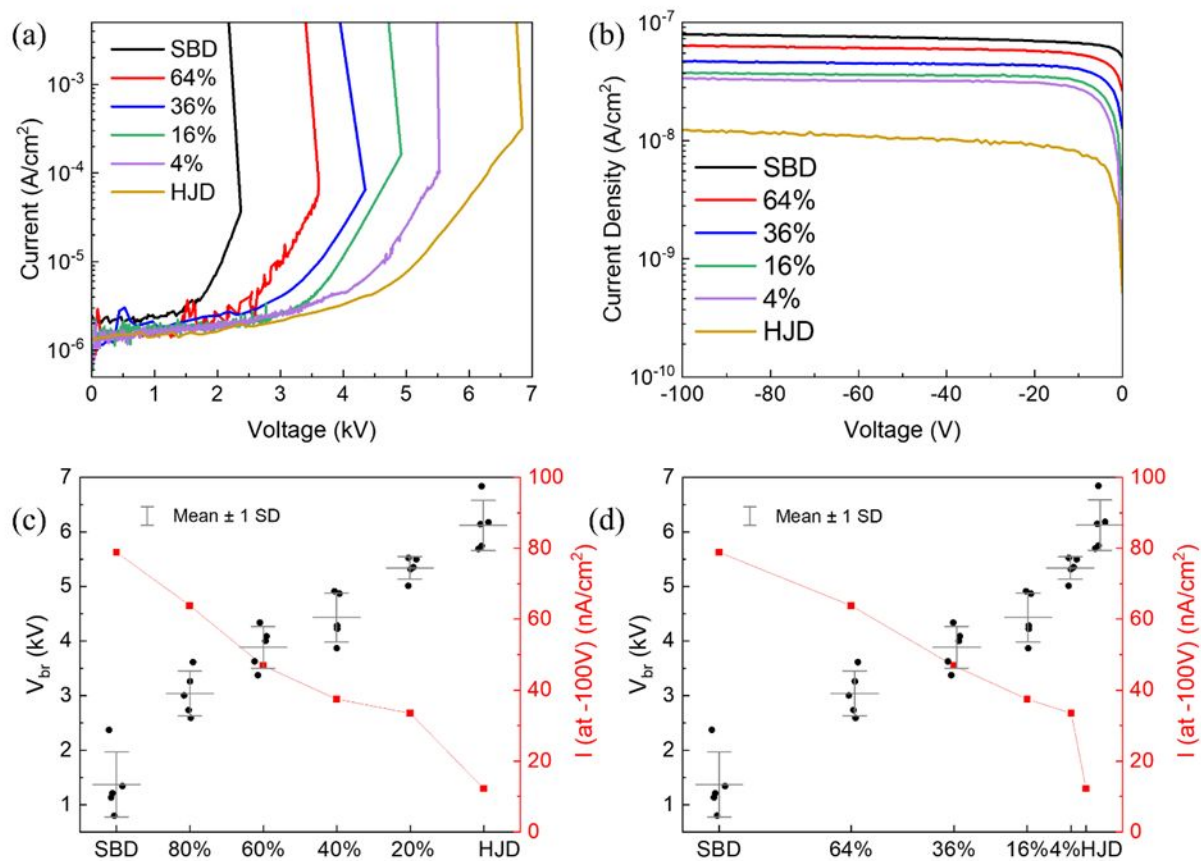
As shown in **Figure 5**, at +1 V, the direct thermionic emission of electrons from  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> to the Ni Schottky contact dominates for the 16%, 4%, and 64% hybrid junction diodes. However, when the applied voltage is increased to +4 V, a new mechanism appears in the 16% and 4% hybrid junction diodes. This mechanism involves the transfer of electrons from  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> to NiO, and subsequently to the Ni contact, by thermionic emission. In contrast, this mechanism is less

1 dominant in the 64% diode due to the thicker rings and reduced contact area between NiO and Ni.  
2 Thus, we conclude that the transitions in the slopes of the linear regions at high forward voltages  
3 in the 16% and 4% hybrid junction diodes are attributed to the transition of electrons from  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>  
4 to NiO and then to the Ni contact by thermionic emission. In addition, this confirms the reason for  
5 the nonlinear behavior of the forward current at 5V at different Schottky contact areas as we  
6 discussed in **Figure 3 (c)**. This behavior in electron flow also explains the non-linear variation of  
7 the  $V_{on}$  with the Schottky contact area. For SBDs covering less than 60% of the contact area, we  
8 observed that the  $V_{on}$  value closely matches that of a standard SBD. This can be attributed to the  
9 dominant thermionic emission of electrons from the  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> to the Ni contact. However, as the  
10 SBD area decreases and the HJ area increases, a new dominant process influences the  $V_{on}$  by the  
11 electrons emission from  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> to NiO, and subsequently to the Ni contact.



**Figure 5.** Electron current density (log scale) for hybrid junction diodes: (a) 4%, (b) 16%, and (c) 64% under 1V; (d) 4%, (e) 16%, and (f) 64% under 4V.

The reverse breakdown characteristics from the set of devices are shown in **Figure 6(a)**. The breakdown voltage ( $V_{br}$ ) increased monotonically as the proportion of heterojunction area increased, from 1.2 kV for Schottky rectifiers to 6.2 kV for pure heterojunction devices. The same trend was seen in the low bias ( $\leq 100V$ ) reverse J-V characteristics of **Figure 6 (b)**. **Figure 6 (c)** shows the area dependence of  $V_{br}$  and reverse current density at a fixed bias voltage of -100 V of the hybrid devices as a function of the Schottky contact area relative to the total area. The same data is shown in **Figure 6 (d)** as a function of the percentage of Schottky contact diameter relative to the total diameter of the hybrid devices. The relationship between breakdown voltage is relatively linear with both area and diameter over parts of the range investigated, with the  $V_{br}$  being linear with percentage area until pure HJDs and for hybrid devices other than pure SBDs. These trends may be an indication that surface effects predominate for Schottky contact devices whereas bulk effects are more important for heterojunction rectifiers. This is reasonable, since in the latter, the NiO would help screen surface states<sup>(5, 40-46)</sup>. The linear dependence of the  $V_{br}$  on the Schottky contact area relative to the total area can be explained by the shift in the electric field from the Ni/Ga<sub>2</sub>O<sub>3</sub> edge in the SBD to the NiO/Ga<sub>2</sub>O<sub>3</sub> edge in the HJ. This shift in the electric field distribution plays a crucial role in controlling the breakdown voltage. As the Schottky contact area decreases, the electric field becomes more concentrated at the NiO/Ga<sub>2</sub>O<sub>3</sub> interface, which in turn affects the  $V_{br}$ . This shifting behavior offers a way to finely tune and control the breakdown voltage values by adjusting the relative size of the Schottky contact area.

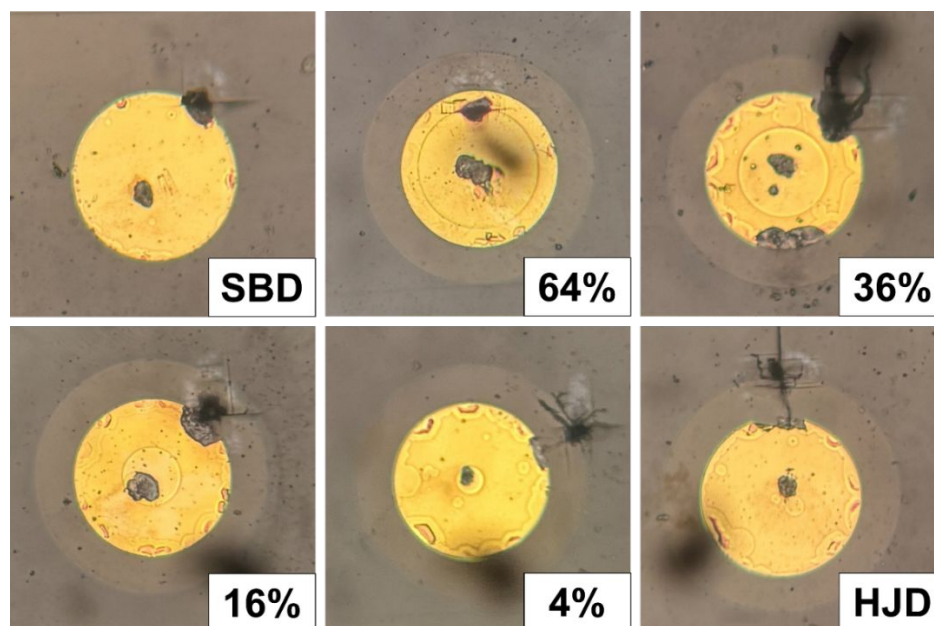


**Figure 6.** Reverse J-V characteristics at high bias (a) and low bias (b) for devices with varying percentages of the Schottky contact diameter. Breakdown voltage (c) and reverse current at -100V bias (d) for devices with different areas and diameters of the Schottky contact within the hybrid devices.

Breakdown mostly was initiated at the edge of the anode contact but could also occur at transition region from the Schottky contact to NiO edge termination. This is seen in the optical images of **Figure 7**. When we purposely drove the devices to failure at their breakdown voltage, pits were observed in the high field regions at the edges of the respective contact regions, either the edge of the Ni/Au anode or at the edge of the Schottky contact contained within that region.



This occurred in SBD at the edge of the metal contact and shifted to the edge of the NiO as the percentage of HJD area increased. For the hybrid JBS devices, the pits were located between the inner and outer edges of the NiO rings, depending on the distance between the metal edge and the NiO edges. For the 64% diode, the pit was located on the inner edge of the NiO, which might be due to it being closer to the metal edge. With a thicker NiO ring, it shifted to the outer side. In addition, we always observed that the pits in the center occurred before the ones on the edge. They were formed around the current density of  $10 \text{ uA/cm}^2$ .



**Figure 7.** Optical images after reverse breakdown of the hybrid devices with varying percentages of the area of the Schottky contact relative to the total area.

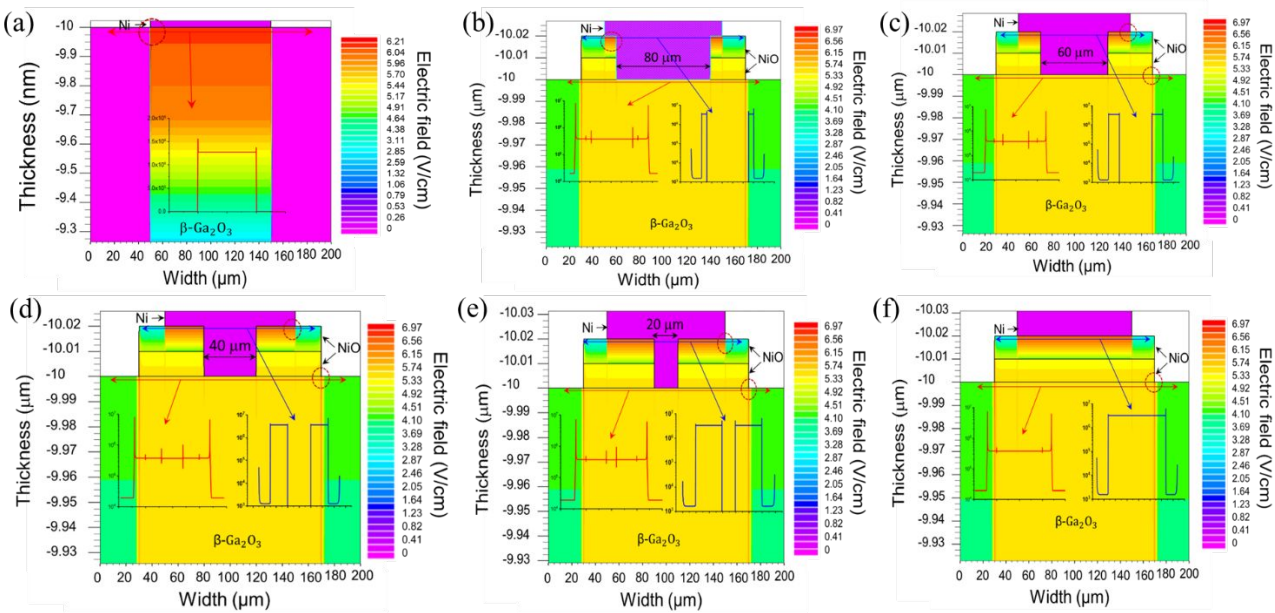
The exact breakdown mechanism in  $\text{Ga}_2\text{O}_3$  is still not established<sup>(12,20,26)</sup>. While avalanche failure at the high fields near the contact periphery is the usual cause in rectifiers of other wide bandgap semiconductors, is not clear what happens with  $\text{Ga}_2\text{O}_3$ , which has a significant component of ionicity to its bonds<sup>(48-50)</sup>. When impact ionization is the breakdown mechanism, this would be

1 characterized by a positive temperature dependence of breakdown on temperature <sup>(51)</sup>. In most  
2 previous materials, like SiC and GaN, this is only observed after many years of device and  
3 materials development to reduce defect density <sup>(33)</sup>. It has not been observed yet in Ga<sub>2</sub>O<sub>3</sub> <sup>(12,26)</sup>.  
4 Even more importantly, it is suggested that since Ga<sub>2</sub>O<sub>3</sub> has a large component of ionicity in its  
5 bonds <sup>(47-49)</sup>, it may not breakdown by impact ionization, but more like an oxide, where direct  
6 bond-breaking occurs <sup>(50)</sup>. That would mean that the models for estimating Ecrit from breakdown  
7 voltages would not apply to Ga<sub>2</sub>O<sub>3</sub>. The degree of ionicity in Ga<sub>2</sub>O<sub>3</sub> can be estimated based on the  
8 electronegativity difference between the atoms involved in the bonding. Ga is a metal, and O is a  
9 nonmetal. To calculate the degree of ionicity, one uses the Pauling scale of electronegativity <sup>(51)</sup>.  
10 The electronegativity of Ga is around 1.81, and the electronegativity of O is around 3.44 <sup>(51)</sup>. The  
11 electronegativity difference ( $\Delta EN$ ) between Ga and O in Ga<sub>2</sub>O<sub>3</sub> is:  $\Delta EN = \text{Electronegativity of}$   
12  $\text{O} - \text{Electronegativity of Ga} = 3.44 - 1.81 = 1.63$ . When the electronegativity difference is greater  
13 than 1.7, the bond is considered predominantly ionic. In this case, the electronegativity difference  
14 is significant, indicating that the Ga-O bonds in Ga<sub>2</sub>O<sub>3</sub> have a significant degree of ionicity.

15 Another expected breakdown mechanism, especially for type II heterojunctions, is the  
16 Zener breakdown mechanism. This phenomenon occurs when the reverse voltage applied across  
17 the diode exceeds a critical value, leading to a significant increase in reverse current <sup>(52)</sup>. This  
18 process is primarily driven by the strong electric field in the depletion region. For example, the  
19 NiO/Ga<sub>2</sub>O<sub>3</sub> heterojunction exhibits type II behavior <sup>(12)</sup>, which may facilitate the tunneling of  
20 electrons from the valence band of the p-type NiO to the conduction band of the n-type Ga<sub>2</sub>O<sub>3</sub>. In  
21 type II heterojunctions, the conduction band minimum of the n-type material is at a higher energy  
22 level than the valence band maximum of the p-type material, which enhances this tunneling  
23 process <sup>(52)</sup>.



To understand the breakdown mechanism, electric field profiles for hybrid devices with varying percentages of the area of the Schottky contact relative to the total area were extracted using Silvaco TCAD. As we can see in **Figure 8(a)** and in the inset of **Figure 8 (a)**, the electric field peak is located at the edge of the Schottky barrier diode, and this agrees with the observed pits in the optical image. Then with decreasing Schottky contact area relative to the total area, we noticed that there are three formed peaks. The first peak is located in the inner edges of the NiO ring and the second peak in the outer edges of the NiO ring and other peak in the edge of NiO/Ga<sub>2</sub>O<sub>3</sub> as shown in **Figures 8 (b)-(f)** and in the inset of **Figures 8 (b)-(f)**. As shown in the insets of **Figure 8**, with the decreasing Schottky contact area relative to the total area, the electric field intensity at the surface of Ga<sub>2</sub>O<sub>3</sub> near the outer edge of NiO increases significantly. This effect is especially pronounced in the case of the NiO/Ga<sub>2</sub>O<sub>3</sub> heterojunction (approximately  $\sim 10^7$  V/cm), confirming the observed pits in all cases. Note that the field distributions in the Ga<sub>2</sub>O<sub>3</sub> under the contact are relatively uniform, The primary reason for this is the small thickness of the NiO layers used. When thicker layers ( $> 50$  nm) are used, there is a larger extent of the field in the Ga<sub>2</sub>O<sub>3</sub>, leading to multiple peaks in the field distribution, as reported previously <sup>(25, 36)</sup>.

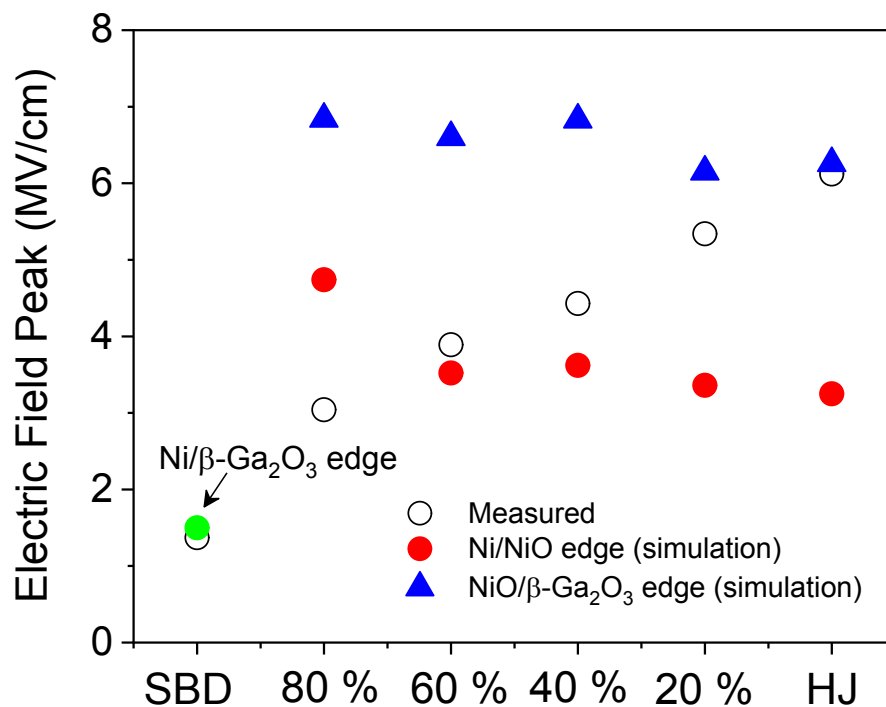


**Figure 8.** Electric field profiles for (a) Schottky diode, (b) 64%, (c) 36%, (d) 16%, and (e) 4% percentages of the area of the Schottky contact relative to the total area, and (f) NiO/Ga<sub>2</sub>O<sub>3</sub> heterojunction. The insets show cutlines of the electric field at the surface of Ga<sub>2</sub>O<sub>3</sub> and near the inner and outer edges of the NiO rings for each case under high reverse voltage.

As shown in **Figure 9**, the extracted electric field peak from the measurements exhibits a linear dependence on the Schottky contact relative to the total area, which is derived from the breakdown voltage value ( $E_{\text{Peak}} = V_{\text{br}}/d$ , where  $d = 10 \mu\text{m}$  (epitaxial film thickness)). As previously discussed, the electric field peak shifts from the Ni/Ga<sub>2</sub>O<sub>3</sub> edge in the case of the SBD to the NiO/Ga<sub>2</sub>O<sub>3</sub> edge in the case of the HJ. Simulated electric field peaks, extracted from the inset of **Figure 8**, also occur at the Ni/Ga<sub>2</sub>O<sub>3</sub> and NiO/Ga<sub>2</sub>O<sub>3</sub> edges.

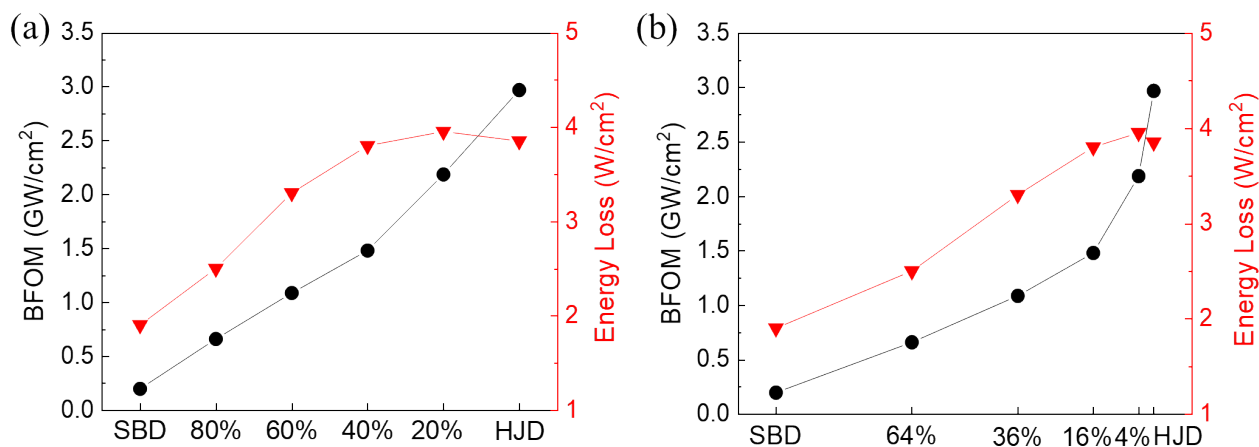
When comparing the simulations with the measurements, we observed that for the SBD, the simulated electric field peak values closely align with those extracted from the measurements. As the Schottky contact relative to the total area decreases, the electric field peak located at the Ni/

1  $\text{Ga}_2\text{O}_3$  edge also decreases. The simulated values for the cases of 80%, 60%, and 40% Schottky  
 2 contact area show strong agreement with the measured values at the  $\text{Ni}/\text{Ga}_2\text{O}_3$  edge. However,  
 3 when the Schottky contact area is reduced to 20%, we observed that the simulated electric field  
 4 peak extracted from the  $\text{NiO}/\text{Ga}_2\text{O}_3$  edge closely matches the value obtained from the  
 5 measurements.



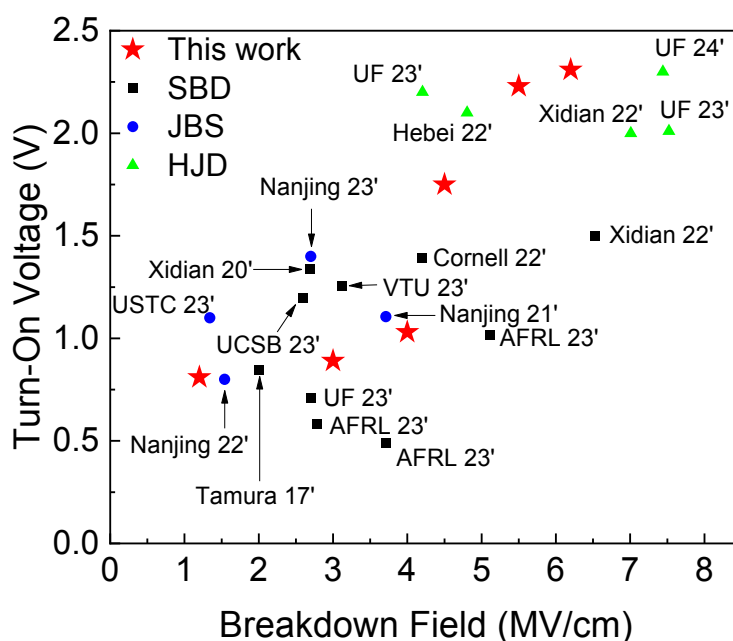
6  
 7 **Figure 9.** Comparison of the electric field peak extracted from measurements with simulated  
 8 values at both the  $\text{Ni}/\text{Ga}_2\text{O}_3$  and  $\text{NiO}/\text{Ga}_2\text{O}_3$  edges.

Now, **Figure 10 (a)** shows the area dependence of the Baliga figure of merit and energy loss during switching of the hybrid devices as a function of the Schottky contact area relative to the total area. The same data is shown in **Figure 10(b)** as a function of the percentage of Schottky contact diameter relative to the total diameter of the hybrid devices. The power figure of merit scales almost linearly with device diameter, reflecting the trend of breakdown voltage.



**Figure 10.** Baliga figure of merit and energy loss for hybrid devices with varying percentages of the area (a) or diameter (b) of the Schottky contact relative to the total area or diameter.

The turn-on voltage in rectifiers causes a reduction in efficiency and increased thermal losses (11,41,42). Apart from the JBS rectifiers described here, other configurations that produce a reduced surface electric field at the anode and reduced increase in turn-on voltage include trench-Schottky barrier diodes, trench-MOS barrier diodes and metal-dielectric-semiconductor (MDS) diodes employing high permittivity dielectrics and negative conduction band offsets (11,41,42). **Figure 11** summarizes the trade-off between breakdown voltage and  $V_{ON}$  reported recently from various groups (20- 27, 36-40). For comparison, a commercially available SiC JBS rectifier has a  $V_{ON}$  near 1V and a breakdown field of  $\sim 2.5$  MV/cm (12). The higher breakdown fields of  $Ga_2O_3$  do come at the cost of higher  $V_{ON}$ . Recent work on incorporating interlayers of TiN have shown the ability to tune the  $V_{ON}$ - $V_B$  tradeoff (42).



**Figure 11.** Summary of  $V_{on}$  results as a function of breakdown field in various types of vertical geometry  $\text{Ga}_2\text{O}_3$  rectifiers reported by various groups.

## Summary and Conclusions

The incorporation of NiO as a p-layer to provide JBS or heterojunction rectifiers, or as an edge termination material, significantly improves the breakdown voltage and lowers reverse leakage current<sup>(20-26, 36-42)</sup>. However, this also leads to higher turn-on voltage and switching losses. The trends in various device parameters for hybrid Schottky/heterojunction  $\text{Ga}_2\text{O}_3$  rectifiers were examined as a function of the ratio of area or diameter of the Schottky contact relative to the total device area or perimeter. Schottky rectifiers have lower turn-on voltages but lower breakdown voltages relative to the heterojunction devices. Breakdown still occurs mostly at the anode edge, but in some cases, can also occur at the internal metal contact boundary in hybrid devices. Continued optimization of the edge termination<sup>(12)</sup> and switching characteristics<sup>(41)</sup> are still

1 needed to establish the operating conditions under which Ga<sub>2</sub>O<sub>3</sub> rectifiers will have advantages  
2 over SiC.

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15 Investigation (equal); Methodology (equal), Writing – original draft (equal)

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17 Investigation (equal); Methodology (equal), Writing – original draft (equal)

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19 (equal); Methodology (equal), Writing – original draft (equal)

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22 Investigation (equal); Methodology (equal), Writing – original draft (equal)

23 **Authors Contributions**

## Declarations

The authors have no conflicts to disclose.

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## Data Availability

The data supporting this article have been included as part of the Supplementary Information.

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The data supporting this article have been included as part of the Supplementary Information.